

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Venkat Selvamanickam, et al.

Title: METALORGANIC CHEMICAL VAPOR DEPOSITION (MOCVD)
PROCESS AND APPARATUS TO PRODUCE MULTI-LAYER HIGH-
TEMPERATURE SUPERCONDUCTING (HTS) COATED TAPE

App. No.: 10/602,468 Filed: June 23, 2003

Examiner: Aaron Austin Group Art Unit: 1775

Customer No.: 34456 Confirmation No.: 2661

Atty. Dkt. No.: 1014-SP156-US

MS AMENDMENT
Commissioner for Patents
PO Box 1450
Alexandria, VA 22313-1450

RESPONSE TO OFFICE ACTION

Dear Sir:

In response to the Office Action mailed October 2, 2007, please amend the above-identified application as follows: